

PRODUCT/PROCESS CHANGE NOTICE (PCN)

PCN #: 1500 01	ΔΑΤΕ ·	2-Oct-2015	MEANS OF		HANGED DEVICES:
Product Affected: PDIP-28 Refer to Attachment II for the a	DATE:	numbers	 Product M Back Mar Date Code Other 	lark Lot # will hav k "V" prefix for	re: • MMT, Thailand
Date Effective:2-Jan-2016					
Contact: IDT PCN DESK			Attachment:	Yes	D No
E-mail: <u>pcndesk@idt.com</u>			Samples: Plass	ease contact your local nple request.	sales representative for
DESCRIPTION AND PURPOSE OF C	HANGE:				
 Die Technology Wafer Fabrication Process Assembly Process Equipment Material Testing Manufacturing Site Data Sheet Other 			ng Millennium Microtech d		
RELIABILITY/QUALIFICATION SU Refer to qualification data shown in Attac	MMARY: chment I.				
CUSTOMER ACKNOWLEDGMENT OF RECEIPT: IDT records indicate that you require written notification of this change. Please use the acknowledgement below or E-Mail to grant approval or request additional information. If IDT does not receive acknowledgement within 30 days of this notice it will be assumed that this change is acceptable. IDT reserves the right to ship either version manufactured after the process change effective date until the inventory on the earlier version has been depleted.					
Customer:			Approve	el for shipments pr	ior to effective date.
Name/Date:		E-	Mail Address		
Title: Phone# /Fax# :					
CUSTOMER COMMENTS:					
IDT ACKNOWLEDGMENT OF RECEIPT:					
RECD. BY:			DATE:		



Integrated Device Technology, Inc. 6024 Silver Creek Valley Road, San Jose, CA - 95138

PRODUCT/PROCESS CHANGE NOTICE (PCN)

ATTACHMENT I - PCN # : A1509-01

PCN Type:	Manufacturing Site - Alternate Assembly Location
Data Sheet Change:	None
	No change in moisture sensitivity level (MSL)

Detail Of Change:

This notification is to advise our customers that IDT is adding MMT, Thailand as the alternate Assembly facility.

The material set details of the current and alternate assembly location is as shown in Table 1. The die attach and mold compound used at the alternate assembly are qualified IDT materials. There is no change from the existing qualified lead frame material, lead finish, and wire for the alternate assembly location.

There is no change to the moisture performance.

Table 1: Assembly Material Sets for The Existing and Alternate Assembly Location

	Existing Assembly (Amkor, Philippines)	Alternate Assembly (MMT, Thailand)
Die Attach	8390A	CRM1064L
Wire	Au wire	Au wire
Mold Compound	CK5000A	GE800

Qualification Information and Qualification Data:

Affected Packages:	PDIP-28
Assembly Material:	The affected package type is using MMT standard materials shown on page 2 of this attachment.
Qual Plan & Results:	Tests are in accordance with JEDEC47 recommended tests.

Qualification Vehicle: PDIP-28

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Test Description	Test Method	Test Results (Rej / SS)			
rest Description	rest wrethou	Lot 1	Lot 2	Lot 3	
* Temperature Cycling (-55°C to 125°C, 700 cycles)	JESD22-A104	0/25	0/25	0/25	
* HAST - unbiased (130 °C/85% RH, 96 Hrs)	JESD22-A110	0/25	0/25	0/25	
High Temperature Storage Bake (150°C, 1000 Hrs)	JESD22-A103	0/25	0/25	0/25	
Physical Dimensions	JESD22-B100	0/25	0/25	0/25	

Tests were subjected to Preconditioning per JESD22-A113 prior to stress test



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ATTACHMENT II - PCN # : A1509-01

Affected Part Numbers

Part Number	Part Number	Part Number	Part Number
71256SA12TPG	7204L12TPG	7201LA12TPG	7164L20TPGI
7201LA35TPG	7205L12TPG	71256SA15TPG	7164S20TPG
7201LA50TPG	7205L15TPGI	71256SA15TPGI	7164S20TPGI
7202LA12TPG	7206L15TPG	71256SA20TPG	7164S25TPG
7202LA15TPGI	7206L20TPGI	71256SA20TPGI	7200L12TPG
7203L12TPG	72200L10TPG	71256SA25TPG	7200L15TPGI
7203L15TPGI	7201LA25TPG	71256SA25TPGI	72240L10TPG

Package Comparizon between Current and Alternate New Assembly

		Current Site	New Site	Comment
	Pkg and Si Attribute	ATP	ММТ	
	Pkg type	PTG28	PTG28	No change
Pkg	Pkg x & y (inches)	Package Length: 1.365 ± 0.02 & Package width: 0.285 ± 0.010	Package length: 1.375 (min), 1.385 (max), Package width: 0.279 (min), 0.289 (max)	Within IDT POD specification.
	Pkg z (inches)	Min: 0.120, Max: 0.150	Min: 0.125, Max: 0.135	Within IDT specification.
	Max Voltage	NA	NA	NA
	Capacitors	NA	NA	NA
	Si Process	No change	No change same wafer	No change
	Wafer Size	No change	No change same wafer	No change
	Die size (mm2)	No change	No change same wafer	No change
	Die Aspect Ratio	No change	No change same wafer	No change
	Die thickness (mils)	No change	No change same wafer	No change
	Polyimide (Y/N)	No change	No change same wafer	No change
	Silicon Metal Layers	No change	No change same wafer	No change
	Scribe Width (um)	No change	No change same wafer	No change
2	UBM source	No change	No change same wafer	No change
~~~~~~~~~~~~~~~~~~~~~~~~~~~~~~~~~~~~~~~	Silicon UBM Stack-up	No change	No change same wafer	No change
Ē	Bump source	No change	No change same wafer	No change
lico	Bump pitch	No change	No change same wafer	No change
S	I/O & Core (um)	No chango	No chango samo wafor	No chango
	Rump Diameter	No change	No change same water	No change
	Bump Hoight	No change	No change same water	No change
	Bump Motollurgy	No change	No change same water	No change
	Mofor Duran Flux	No change	No change same water	No change
		No change	No change same water	No change
	Lindorfill Matorial	No change	No change same water	No change
		No change	No change same water	No change
	Halagan Eros 2	NA NA	NO Change Same water	
	Substrate Lavers	NA	NA	NA
	Substrate thickness	NA	NA	NA
	Core thickness (um)	ΝΔ	NA	ΝΔ
	Core Material	NA	NA	NA
	Outer layer Lines/space	NA	NA	NA
	Bump Pre-solder (SOP)	NA	NA	NA
	Bump presolder (SOP) height/diameter	NA	NA	NA
Ċ,	Bump Capture Pad/SRO IO (um)	NA	NA	NA
strate	Substrate Ball Capture Pad/SRO (um)	NA	NA	NA
Sub	Number of PTH/M1-M2 uVias	NA	NA	NA
	Core PTH/Capture pad (um)	NA	NA	NA
	Substrate Design Rule & BOM	NA	NA	NA
	Substrate Supplier	NA	NA	NA
	Build up layer (thickness)	NA	NA	NA
	Solder mask (thickness)	NA	NA	NA
	C1 & C4 thickness (plate)	NA	NA	NA
	C2 & C3 thickness (foil + plate)	NA	NA	NA
	Surface finish (thickness)	NA	NA	NA
	2nd level Ball count	NA	NA	NA
	2nd level BA Flux	NA	NA	NA
SLI	2nd Ball Dia (mm)	NA	NA	NA
	2nd level metallurgy	NA	NA	NA
	2nd level ball pitch (mm)	NA	NA	NA